



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE  
(Case No. MMD98010CONDIV)

In the Application of:	)	
	)	
Vlasta Brusic Kaufman et al.	)	Examiner: George Goudreau
	)	
Serial No.	)	
10/616,335	)	
	)	Group Art Unit: 1763
Filed:	)	
July 9, 2003	)	
	)	
Title:	)	
Chemical Mechanical Polishing	)	
Slurry Useful for Copper	)	
Substrates	)	

**REPLY TO MARCH 25, 2005 OFFICIAL ACTION**

Commissioner of Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

This is a Reply to the March 25, 2005 Official Action for the above-captioned U.S. patent application.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks** begin on page 5 of this paper.

**Appendix A** which includes a copy of a Terminal Disclaimer filed in this case follows page 6 of this Reply.